Electronic Parts Engineering Section 507

Laboratory Facilities Instruction

(JPL D-15854)

Radiation Test and Failure Analysis Group

JPL Electronic Parts Engineering Section

Reviewed and Approved by:_

Dr. Charles Barnes

Supervisor

Radiation Test and Failure Analysis Group JPL Electronic Parts Engineering Section

PROCESS: Electronic Parts Engineering (Section 507) Laboratory Facilities Operation and Maintenance

SCOPE: This document records the nominal processes required to operate and maintain laboratory facilities for the Electronic Parts Engineering Office (Section 507).

APPLICABILITY: The procedures recorded in this document apply to users of the laboratory facilities listed in the following table.

Laboratory Facility	Location	Cognizant Engineer	Phone
Failure Analysis (FA)	300-110	Sid Johnson	x4-2298
Scanning Electron Microscope (SEM)	300-108	Ken Evans	x4-4834
Parts Evaluation (PE)	300-127	Mike O'Connor	x4-5595

FACILITY MANAGEMENT: The group supervisor in charge of the listed facilities is Dr. Charles E. Barnes, M/S 303-200, Ph#: x4-4467.

DOCUMENT CHANGE LOG

Issue	Date	Approval	Affected Pages
JPL D-15854 Original			All

Section I.

REGULARLY SCHEDULED FACILITY MAINTENANCE PROCEDURES - A time based hierarchy of operational procedures for the facilities is explained in this section. The relevant facility process is shown in *bold-italicized* font and further elaboration of the procedures can be found in Section II of this document.

1. Daily Procedures:

- 1. Restoring Facility Operations From Shutdown
 - 1. Safety Checks Do not enter the facility if the following conditions exist:
 - a. Alarm (flashing red lights and horn) for oxygen monitor is tripped.
 - b. An obvious safety hazard exists (e.g., posted warning)
 - 2. *Equipment* Maintenance Perform procedures required to maintain the operability of laboratory equipment.
- 2. Facility Shutdown To be performed at the end of the work day.
 - 1. *Safety* Checks The last employee leaving the facility must perform a walk-through check of the facility to ensure that all equipment and utilities are secured for a safe overnight shutdown. Facility doors are required to be locked during the overnight shutdown period.
 - 2. Storage Procedures The facility staff are responsible for ensuring that ongoing tasks are properly stored during the shutdown period. Special handling (e.g., emergency notification) procedures for tests in progress that require equipment to operate during the overnight period shall be indicated on a posted sign.

2. Weekly Procedures:

- File Backups Make back-up copies at the end of the week of electronic files that support facility operations. This procedure is generally conducted at the end of the work week.
- Safety Maintain a resonably clean and safe working environment by clearing away unecessary clutter and and disposing of debris. This procedure is generally conducted at the end of the work week.
- 3. *Utilities* Facility users are responsible for consulting "JPL This Week" for any utility interruptions that will impact ongoing work. This procedure is generally conducted at the end of the work week.

3. Monthly Procedures: - None.

4. Annual Procedures:

- 1. Safety Note: Scheduling of the various audits is at the discretion of the inspecting agency.
 - 1. JPL Safety Operations Section (SOS) Audit
 - 2. Audits by Other Agencies (e.g., OSHA)
 - 3. Staff Training and Certification JPL required staff training/certification to be performed as deemed necessary by the cognizant training organization.

2. Equipment

- 1. Property Inventory Annual property inventory scheduled by JPL.
- 2. Capital Equipment Plan -A capital equipment plan prepared in accordance with JPL guidelines for the acquisition of new/upgraded equipment. This procedure is performed on a schedule determined by Section 507 in cooperation with the funding agency(ies).
- 3. Maintenance Contracts Renewal of annual maintenance contracts for equipment that is to be serviced by vendors outside of JPL. This procedure is performed on a schedule determined by the affected service contracts.

5. Performed As-Needed Procedures:

- 1. Ordering *Supplies* Staff members are responsible for ordering and maintaining an adequate stock of consumables.
- 2. Calibration of *Equipment* Equipment calibration is to be performed as required to support tasks performed in the facilities.
- 3. **Storage** of toxic/hazardous wastes The handling and disposal of toxic/hazardous wastes shall be in accordance with all applicable regulatory guidelines as communicated to the staff by JPL's System Safety Office.
- 4. Plant Maintenance/Repair Notification The staff shall notify JPL Plant Maintenance in the event of conditions that require their attention.
- 5. Updates to Documentation Self explanatory.

Section II.

GENERAL FACILITY PROCESSES - The following table describes the processes used to operate and maintain the facilities.

PROCESS	Process Component	Component Description	Cognizant
EQUIPMENT	Equipment List	A list of functional equipment with general operating procedures is maintained under the cognizance of the Radiation Test and Failure Analysis Group supervisor. The list identifies the primary operator and location of equipment in the facilities. Revisions to the equipment list are made at the discretion of the cognizant group supervisor. The current list is attached to this document as Appendix I.	C. Barnes
	Equipment Maintenance and Calibration	Regularly scheduled equipment maintenance and calibration is performed in accordance with the manufacturer's recommendations. Additional requirements for testing / examination / analysis of flight equipment are at the discretion of the requesting project.	Primary Equipment Operators
	Capital Equipment Plan	Equipment purchase plans are prepared in accordance with JPL guidelines.	C. Barnes
FILE	Equipment Manuals and Calibration Certificates	Equipment operation manuals, service manuals and calibration certificates are maintained in the facility files unless noted otherwise in the Current Equipment List.	Primary Equipment Operators
	Specifications and Standards	Reference copies of regularly utilized specifications and standards referenced and/or required in tasks supported by the facilities are maintained in the facility files or are accessible electronically via online resources. Controlled copies are available from JPL documentation via on-line resources.	C. Barnes

PROCESS	Process Component	Component Description	Cognizant
FILE (cont'd)	Work Order and Task Log Book(s)	A database(s) that enables the documentation of tasks submitted to the facility is maintained. The database(s) includes the ability to track labor charges and other costs associated with specific tasks. Backup copies of essential files are to be made on a weekly basis.	Facility Users
	SEM micrograph negatives	The SEM facility provides archival storage of micrograph negatives.	K. Evans
	Material Safety Data Sheets (MSDS)	All facilities containing controlled / hazardous materials maintain a binder containing the applicable MSDSs.	Safety Coordinator
SAFETY	Cleaning and General Housekeeping	Users of the facility have the responsibility to maintain a reasonably clean and safe work environment.	Facility Users
	Facility Alarms and Emergency Announcements	The facility must be vacated when the low oxygen alarm or fire alarm sound. Facility users must comply with official JPL instructions announced via the paging system in response to emergencies.	Facility Users
	Training and Certification	The applicability of training requirements and records of such training and/or certification are the responsibility of the section safety coordinator. Record of such inspections are maintained by the cognizant inspecting agency.	Safety Coordinator
	Facility Access	Access to the facilities is not controlled. All unescorted visitors to the facility are expected to obey all posted warnings.	Safety Coordinator

PROCESS	Process Component	Component Description	Cognizant
SAFETY (cont'd)	Required Inspections	Inspections of laboratory resources to ensure safe operations (e.g., fume hoods, radiation sources/shielding, oxygen monitors, fire extinguishers, etc.) are performed in accordance with applicable JPL and/or government regulations on a schedule determined by the inspecting agencies. Records of such inspections are maintained by the cognizant inspecting agency.	Safety Coordinator
	End of Shift Inspection	Perform facility walk-around inspection to ensure all equipment is secured and that a safe condition exists for facility shut-down.	Facility Users
STAFF	Radiation Test and Failure Analysis Group	A database of personnel assigned to operate and maintain the facility. The database includes emergency notification provisions (e.g., ph. #, pager, e-mail, etc.) and the facility hierarchy for contingency operations.	Section Office
STORAGE Work In-Progress		Storage shelves and file cabinets and work benches for securing work in-progress are provided in the facility. Applicable signs are posted to alert other users of the facility to any special handling precautions.	Facility Users
	Equipment	Storage shelves and work benches are utilized to store moveable equipment used in the execution of tasks within the facility.	Facility Users and Primary Equipment Operators
	Chemical and Material	Appropriate storage receptacles/facilities are provided for chemical and material supplies and waste materials in conformance with requirements communicated by the Safety Operations Section.	Safety Coordinator
SUPPLIES	Laboratory Supplies and Consumables	The JPL supply and procurement processes is utilized to maintain adequate provisions for operation of the facility. The scheduled replenishment of facility supplies is at the discretion of the staff and is performed as required.	Facility Users

PROCESS	Process Component	Component Description	Cognizant
UTILITIES	Interruptions and	Check "JPL This Week" for utility interruptions.	Facility
	Contingencies	Notify affected users and formulate contingencies.	Staff and
			Safety
			Coordinator
	Location of Circuit	Facility users trained to recognize the location and	Safety
	Breakers and Shut-off	operation of utility shut-down panels and valves.	Coordinator
	Valves		

Appendix I.

Section 507 Lab Equipment Roster and Operating Procedures

Equipment, Location and Primary Operator	Model	Used For	Notes	Operating Procedure and Document Location
Scanning Electron Microscope (SEM) Location: 300-108C Primary Operator: Ken Evans	Hitachi S-4000	High Resolution imaging of surfaces and elemental analysis	Magnification up to 300,000X and 15 Angstrom resolution. Low KV image capability. Ability to detect elemental composition and distribution in sample for M/Z>boron.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is colocated with the equipment.
Scanning Electron Microscope (SEM) Location: 300-108D Primary Operator: Ken Evans	Cambridge S-250	High Resolution imaging of surfaces and elemental analysis	Magnification up to 100,000X. Ability to detect elemental composition and distribution in sample for M/Z>boron.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is colocated with the equipment.
Scanning Electron Microscope (SEM) Location: 300-108B Primary Operator: Ken Evans	Amray 1830i	High Resolution imaging of surfaces and elemental analysis	Magnification up to 50,000X. Ability to detect elemental composition and distribution in sample for M/Z>boron.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is colocated with the equipment.
Plasma Coater and Etcher Location: 300-108 Primary Operator: Ken Evans	Anatech Hummer 10.2	SEM sample preparation	Sputter coat conductive layer (Au, Au-Pd) on samples. Etch samples using Argon	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the SEM facility files.
Vacuum Carbon/Metal Evaporator Location: 300-108B Primary Operator: Ken Evans	Denton Benchtop Turbo	SEM sample preparation	Evaporate carbonb or metal conductive layers on samples	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the SEM facility files.
Infrared Video Camera System Location: 300-108E Primary Operator: Ronald Ruiz	Inframetrics PM-300	Infrared mapping of samples	Microscopic and Macroscopic capabilities	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is located with the primary operator.
Optical Microscopes Location: 300-110C Primary Operator: Sid Johnson	Olympus AH-30, Leitz	High Resolution visual surface analysis	AHT-B3 with DIC Normarski, Dark Field with video image and polaroid capability. Maximum magnification up to 1500X.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Filar microscope measurement system Location: 300-110C Primary Operator: Sid Johnson	N/A	Applying surface measurements to samples	Used in conjuction with optical microscopes. Measure samples at .1 mil resolution	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual

Appendix to Electronic Parts Engineering Section 507 Laboratory Facilities Instruction (JPL D-15854) Page 10 of 14

Equipment, Location and Primary Operator	Model	Used For	Notes	Operating Procedure and Document Location
				is in the FA facility files.
Wirebond Pull Test System Location: 300-110C Primary Operator: Jim Okuno	Unitek MP-4	Measure pull strengths of internal wires in electronic parts.	Measures destructive and non- destructive wirebond pull strengths from 0.1 grams to 1 kg force	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Macrophot Camera Location: 300-110C Primary Operator: Sid Johnson	Nikon	Visual inspection of samples	Macro-photographic capabilities with polaroids	Consult the primary operator prior to first use for specific instructions.
Laser Trace Cutting System Location: 300-110C Primary Operator: Duc Vu	Alessi REL-4100A	Marking targets for inspection and testing. Used in isolating circuits on ICs.	YAG Laser on Microprobe station. ~1 um dia. Spot minimum	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Computer Imaging System Location: 300-110C Primary Operator: Russell Lawton	PGT Imagist / Sun Sparc5	Digital image acquisition and metrology.	Has interface to acquire SEM images from Hitachi S-4000.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Temperature Humidity Chamber Location: 300-110 Primary Operator: Sid Johnson	Blue M B-2730-Q	Environmental testing (e.g. 85/85)		Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Computer Driven Stage Probe station Location: 300-110 Primary Operator: Sid Johnson	Wentworth PR0201RH	Electrical probing of microcircuits		Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Test vector generator Location: 300-110 Primary Operator: Duc Vu	Step Engineering		This equipment is portable within the facility.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Thermal Ovens Location: 300-110 Primary Operator: Sid Johnson	Delta Design 6400	Thermal Bake-out	High (+200° C) Low (-65° C)	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Vacuum Bakeout Ovens Location: 300-110 Primary Operator: Sid Johnson	VWR 1410D, Thelco Precision Model 19	Thermal vacuum bakeout of components	Uses mechanical vacuum pump.	Consult the primary operator prior to first use for specific instructions.
Pull Tester Location: 300-110C	Unitek	Pull testing of electronic components	Pull test samples up to 5 kg.	Consult the primary operator prior to first use for specific instructions.

Appendix to Electronic Parts Engineering Section 507 Laboratory Facilities Instruction (JPL D-15854)
Page 11 of 14

Equipment, Location and Primary Operator	Model	Used For	Notes	Operating Procedure and Document Location
Primary Operator: Jim Okuno		and assemblies.		
Emission Microscope for Multi-Layer Inspection (EMMI) Location: 300-112 Primary Operator: Duc Vu	EMMI KLA	Detects photon emissions from dielectric breakdown in ICs		Consult the primary operator prior to first use for specific instructions.
ESD Tester Location: 300-112 Primary Operator: Duc Vu	IMCS 5000	Electro-Static Discharge testing in ICs		Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Cabinet X-ray Machine Location: 300-110D Primary Operator: Jim Okuno	Astrophysics Corp. TORREX 150D	Internal structure analysis of sample	Up to 150 KV X-rays	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Particle Impact Noise Detection (PIND) test system Location: 300-110D Primary Operator: Jim Okuno	BW-LPD-B2000/2010	Performing PIND tests per Mil-STD requirements	28 gram max. DUT mass	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Die/Ball Bond Shear Test System Location: 300-110D Primary Operator: Jim Okuno	Bondtest30	Performing Die Shear and Ball Bond shear testing per Mil-STDs.	Up to 5 kg shear force	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Liquid Crystal IC Hot Spot Detection System Location: 300-110 Primary Operator: Robert Gauldin	N/A (Test Method)	Detecting hot spots on failed/defective ICs.		Consult the primary operator prior to first use for specific instructions.
Parallel Plate Plasma Etcher Location: 300-110E Primary Operator: Jim Okuno	Technics	Removing silicon nitride passivation layers from ICs.	Anisotropic Etcher	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Helium Pressure Vessels Location: 300-110E Primary Operator: Jim Okuno		Pressurizing components for hermeticity testing	Up to 150 PSIg	Consult the primary operator prior to first use for specific instructions. Written instructions are located in the FA facility files.
Fine Leak Test System Location: 300-110E Primary Operator: Jim Okuno	Varian Auto-test 947	Performing fine leak hermeticity testing	Sensitivity up to 1E-9 Atm cc/sec He.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual

Appendix to Electronic Parts Engineering Section 507 Laboratory Facilities Instruction (JPL D-15854)
Page 12 of 14

Equipment, Location and Primary Operator	Model	Used For	Notes	Operating Procedure and Document Location
				is in the FA facility files.
Bubble Gross Leak Tester Location: 300-110E Primary Operator: Jim Okuno	Trio-Tech 481	Performing bubble gross leak testing per Mil-Std.		Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Small Machine shop Location: 300-110F Primary Operator: Sid Johnson		In house fabrication for test fixturing and device decapsulation and machining.		Consult the primary operator prior to first use for specific instructions.
Potting and semi-automatic cross sectioning and polishing equipment Location: 300-110A Primary Operator: Robert Gauldin	Struers Rotopol-2 & Rotopol-V	Performing semi- automatic fine cross sectioning of potted samples for examination.	Equipment capable of sectioning 6 samples simultaneously.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Diamond wet grinding wheels Location: 300-110A Location: 300-110F Primary Operator: Robert Gauldin	Leco VP-50	Grinding extremely hard materials such as ceramics		Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
High-speed diamond Saw Location: 300-110B Primary Operator: Robert Gauldin	Struers Accutom-2	Cutting hard ceramic and/or metallic samples.		Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Chemical Hoods (3 ea) Location: 300-110B Location: 300-108 Primary Operator: Sid Johnson		General purpose use	Organic and Non-Organic material Hoods	Consult the primary operator prior to first use for specific instructions.
High temperature Thermal Oven Location: 300-110B Primary Operator: Sid Johnson	Delta 6400	High temperature testing	High (+400° C) Contains Test Lead Ports.	Consult the primary operator prior to first use for specific instructions.
Jet-etch acid plastic part decapsulation system Location: 300-110B Michael O'Connor	NSC PA103	Decapsulating plastic packaged parts without damaging the device		Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
High precision analytical digital scales Location: 300-108 Location: 300-110B Primary Operator: Ronald Ruiz			Resolution to 0.1mg	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the SEM facility files.
Digital Sine Vibration Controller	DSC-1	Vibration and Shock	Range: 5 to 6250 Hz	Consult the primary operator prior to first

Appendix to Electronic Parts Engineering Section 507 Laboratory Facilities Instruction (JPL D-15854)
Page 13 of 14

Equipment, Location and Primary Operator	Model	Used For	Notes	Operating Procedure and Document Location
Location: 300-110D Primary Operator: Duc Vu		Testing	Stability: +/- 100 ppm/C	use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Temperature Cycler Location: 300-110F Primary Operator: Duc Vu	Temptronic	Rapid Temperature cycling of DUTs	-55 to +125° C	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manual is in the FA facility files.
Actel Field Programmable Gate Array (FPGA) programmer Location: 300-112 Primary Operator: Duc Vu	Actel	Programming of Actel FPGAs		Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manuals are co-located with the equipment.
MBT-250A Enhanced Soldering Station Location: 300-127 Primary Operator: Mike O'Connor	PACE MBT-250A	Soldering and Desoldering of electronic components.	Has special tips and fixtures for handling quad flat-packs, thru-holes with precise temperature control.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manuals are co-located with the equipment.
Circuit Board Milling Machine Location: 300-127A Primary Operator: Mike O'Connor	LPKF Promat 93S	CAD/CAM system for the creation of copper traced circuit boards.	Uses a computer controlled milling machine to pattern copper traces on fiberglass circuit boards.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manuals are co-located with the equipment.
Temperature Shock Oven Location: 300-127A Primary Operator: Mike O'Connor	Delta 9080	Performing temperature shock tests on components.	The oven has a shuttle that transfers between a hot and cold oven.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manuals are co-located with the equipment.
Thermal Ovens w/ Power Supplies for Burn-In Location: 300-127A Primary Operator: Mike O'Connor	Delta	For burn-in qualification of electronic components.	Ovens and power supplies rack mounted.	Consult the primary operator prior to first use for specific instructions. The manufacturer supplied instruction manuals are co-located with the equipment.

Appendix to Electronic Parts Engineering Section 507 Laboratory Facilities Instruction (JPL D-15854) Page 14 of 14

Equipment, Location and	Model	Used For	Notes	Operating Procedure and Document
Primary Operator				Location
Sheet Metal Equipment	Various	Sheet metal		Consult the primary operator prior to first
Location: 300-127A		fabrications.		use for specific instructions.
Primary Operator: Mike O'Connor				
Personal Computer Equipment	Various	Various	General purpose computers and	Consult the facility staff prior to first use
Locations: 300-108, 300-110, 300-127			associated peripherals.	for specific instructions.
Primary Operator: Facility Staff				